

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant	:	Granneman et al.
App. No.	:	Unknown
Filed	:	Herewith
For	:	METHOD AND APPARATUS FOR SUPPORTING A SEMICONDUCTOR WAFER DURING PROCESSING
Examiner	:	Unknown
Group Art Unit	:	Unknown

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Enclosed is form PTO-1449 listing 51 references, 13 of which are enclosed, and 38 of which are not enclosed pursuant to 37 CFR § 1.98(d) as they were either cited by or provided to the Patent Office in parent application No. 09/717,702, filed November 20, 2000, from which priority is claimed. This Information Disclosure Statement is being filed within three months of the filing date of this application or upon filing if this is a CPA or RCE, and no fee is required in accordance with 37 C.F.R. § 1.97(b)(1), (b)(2), or (b)(4).

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: June 24, 2003

By: Adel S. Akhtar

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FORM PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. ASMINT.002C3	APPLICATION NO. Unknown
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>  (USE SEVERAL SHEETS IF NECESSARY)		APPLICANT Granneman et al.	
		FILING DATE Herewith	GROUP Unknown

U.S. PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)	
	3,854,443	12/17/74	Baerg				
	3,947,236	3/30/76	Lasch, Jr.				
	4,495,024	1/22/85	Bok				
	4,560,590	12/24/85	Bok				
	4,574,093	3/4/86	Cox				
	4,575,408	3/11/86	Bok				
	4,662,918	11/86	Bok				
	4,662,987	5/5/87	Bok				
	4,903,717	2/27/90	Sumnitsch				
	4,903,754	2/27/90	Hirscher et al.				
	4,958,061	9/18/90	Wakabayashi et al.				
	5,033,538	7/23/91	Wagner et al.				
	5,090,900	2/25/92	Rudolf et al.				
	5,180,000	1/19/93	Wagner et al.				
	5,221,403	6/22/93	Nozawa et al.				
	5,318,801	6/7/94	Snail et al.				
	5,352,294	10/4/94	White et al.				
	5,356,476	10/18/94	Foster et al.				
	5,382,311	1/17/95	Ishikawa et al.				
	5,431,700	7/11/95	Sloan				
	5,447,431	9/5/95	Muka				
	5,520,538	5/28/95	Muka				
	5,542,559	8/6/96	Kawakami et al.				
	5,738,165	4/14/98	Imai				
	5,772,770	6/98	Suda et al.				
	5,778,968	7/14/98	Hendrickson et al.				May 28, 1996
	5,881,208	3/9/99	Geyling et al.				12/20/95

EXAMINER	DATE CONSIDERED
<b>*EXAMINER:</b> INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED. INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.	

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U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)
	5,927,077	7/27/99	Kisai et al.			4/17/97
	5,937,541	8/17/99	Weigand et al.			September 15, 1997
	5,960,159	9/99	Ikeda, et al.			
	5,997,588	12/99	Goodwin et al.			
	6,099,056	8/8/00	Siniaguine et al.			
	6,001,175	12/99	Maruyama et al.			
	6,053,982	4/25/00	Halpin et al.			
	6,183,565	2/6/01	Granneman et al.			
	6,203,622 B1	3/20/01	Halpin et al.			
	6,444,027 B1	9/3/02	Yang et al.			
	US 2001/0037761 A1	11/8/01	Ries et al.			

FOREIGN PATENT DOCUMENTS							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
	8,103,979	3/16/83	The Netherlands				X
	8,200,753	9/16/83	The Netherlands				X
	8,203,318	3/16/84	The Netherlands				X
	8,402,410	3/3/86	The Netherlands				X
		As cited in the Int'l Search Report	Japan - Patent Abstracts of Japan, Vol. 9, No. 85 (E-308), April 13, 1984 & JP 59 2125718 A (Kokusai Denki KK) December 5, 1984; Publication No. 59215718; Publication date May 12, 1984				
	WO 90/13687	11/15/90	PCT				
	WO-98/01890	1/15/98	PCT				
	WO-95/16800	6/22/95	PCT				
	GB 2 181 458 A	10/6/86	United Kingdom				
	0 657 918 A2	11/11/94	EPO				

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		FILING DATE Herewith	GROUP Unknown

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)
	Yoo et al., "Low-temperature annealing system for 300 mm thermal processing," Solid State Technology, June 2001, pp. 152-160
	CRC Hand Book of Chemistry and Physics 3 <sup>rd</sup> electronic edition, CRC Press Inc. publish 2000, p. 6-175
	Chemical Properties Handbook (access via <a href="http://www.knovel.com">www.knovel.com</a> ) McGraw-Hill Companies, 1999

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